



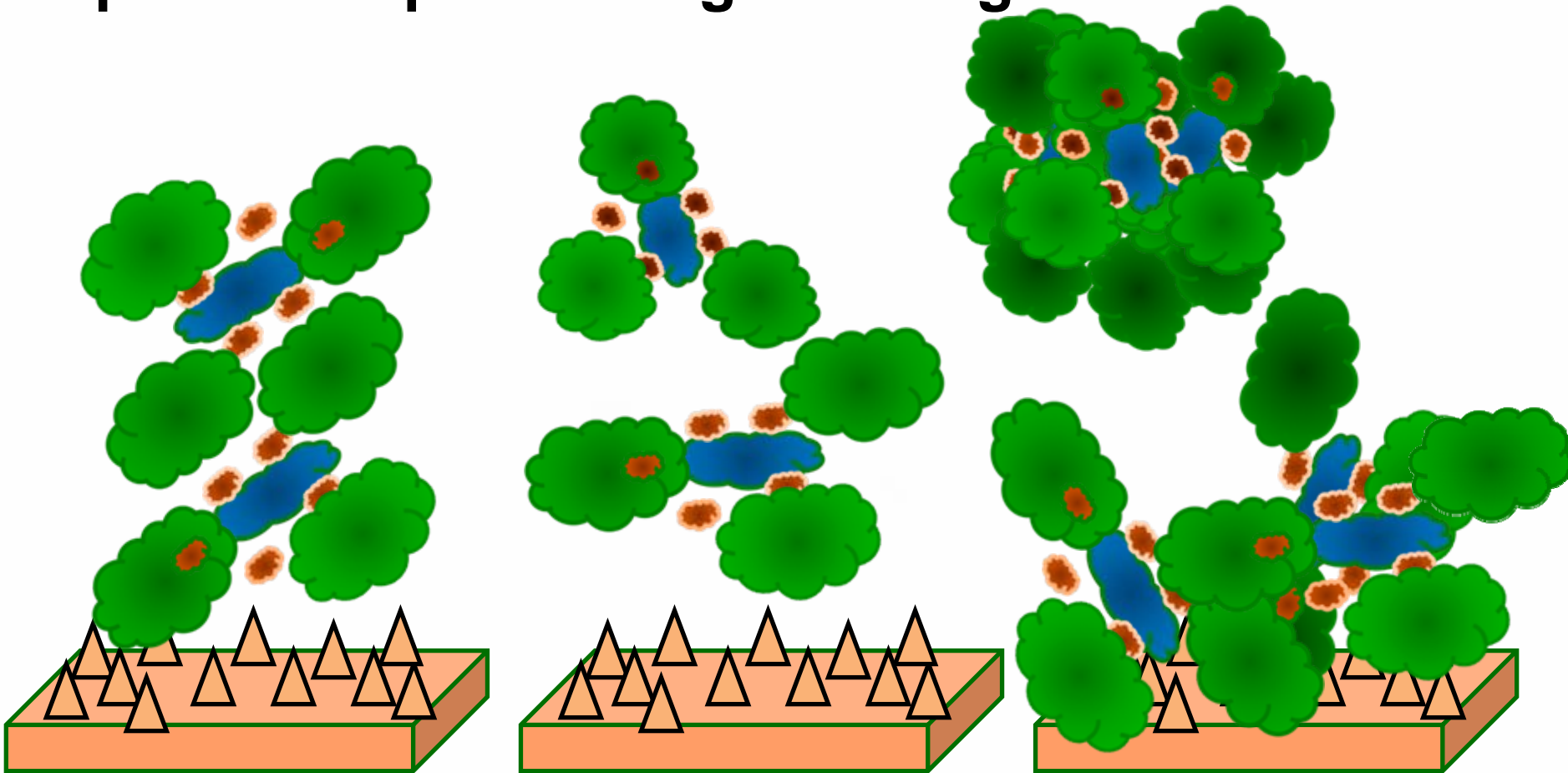
CHEMICAL ENGINEERING

# Pharmaceutical Particle Adhesion to Surfaces

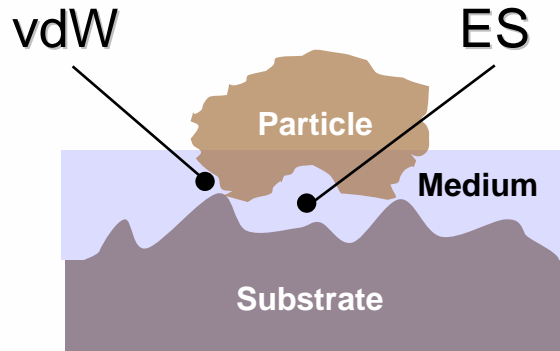
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Purdue University  
W. Lafayette, IN 47906

# Motivation

- Adhesion of pharmaceutical particles critically important to processing of dosage forms



# Fundamental Forces in Particle Adhesion



- **van der Waals (vdW)**

- Interactions between dipoles (and/or induced dipoles)

- **Electrostatic (ES)**

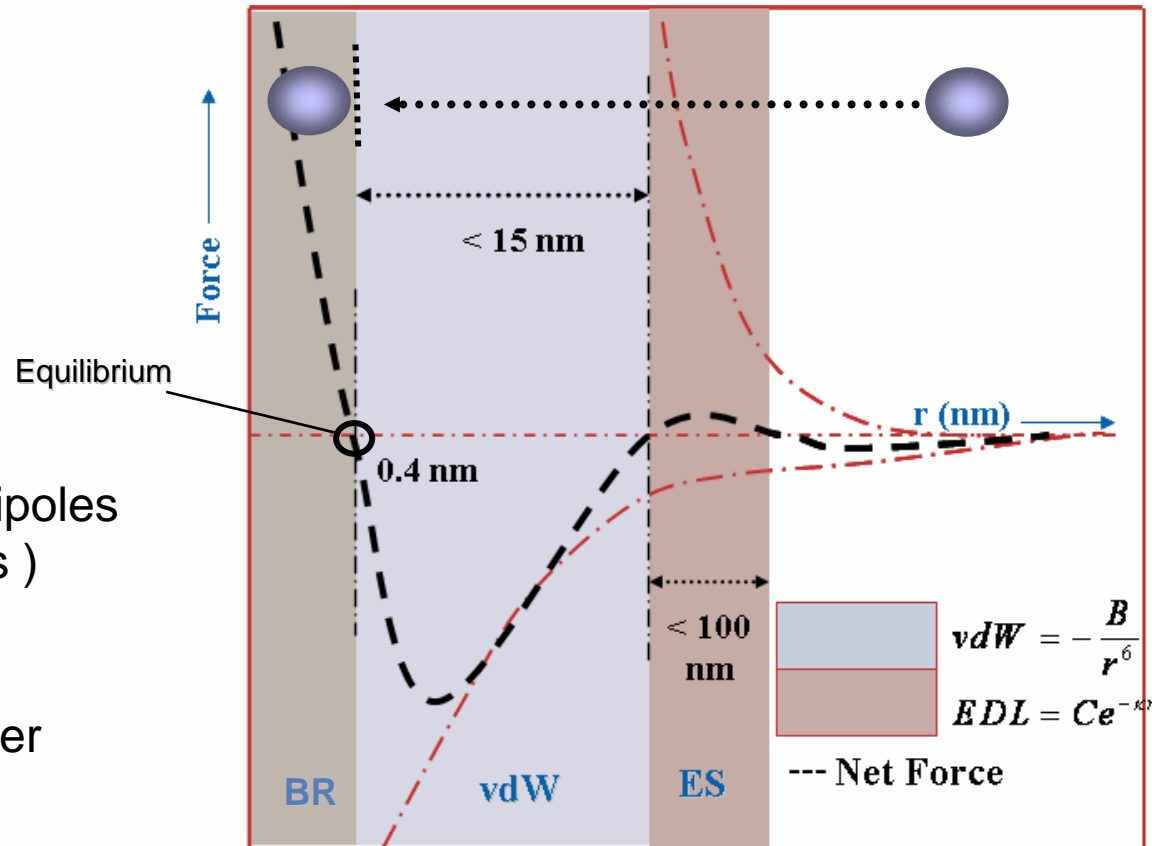
- Columbic or double layer

- Steric force

- Hydrophobic force

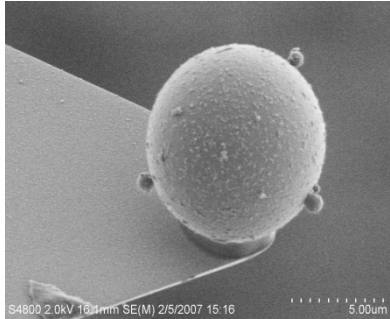
- Chemical bonds

✓ vdW and ES forces are the major contributors in adhesion

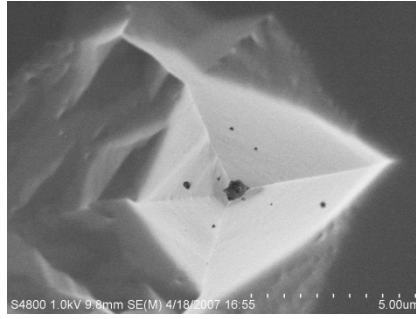


# Adhesion Force Measurements

## Sample Preparation

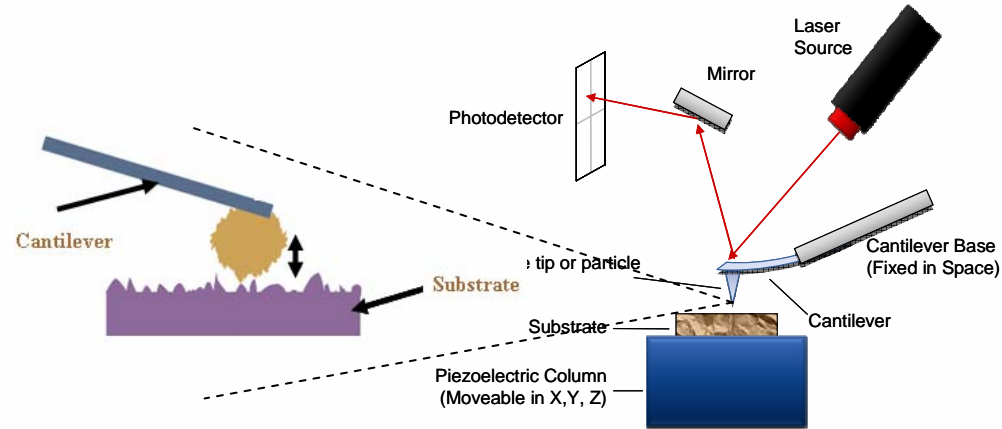


SiO<sub>2</sub> Particle  
(~9μm)

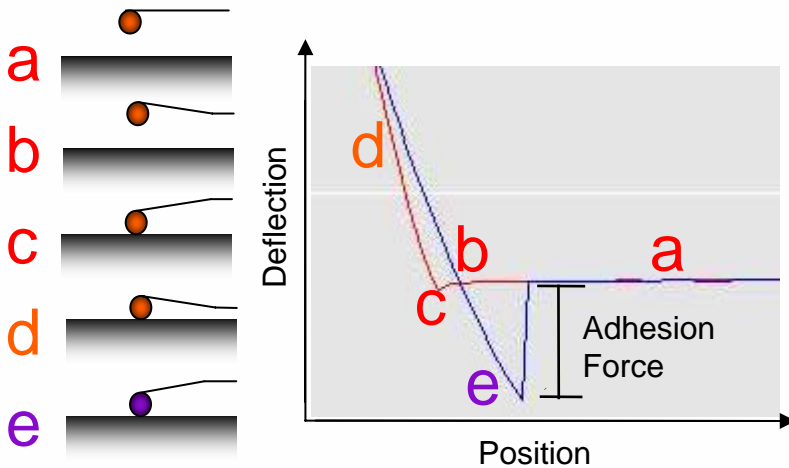


SiO<sub>2</sub> AFM probe (top view)  
(ROC ~50 nm)

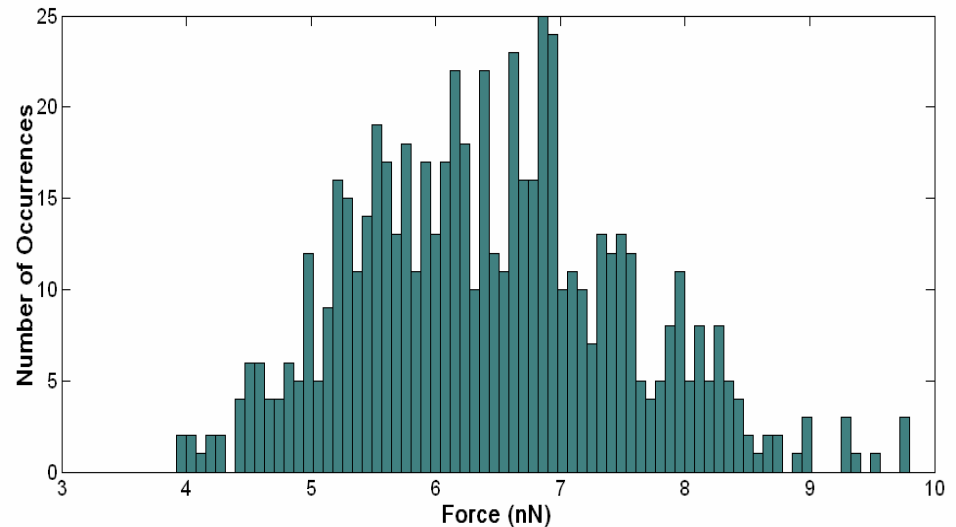
## AFM Force Measurement



## Typical AFM Force Curve



## Measured Force Distribution



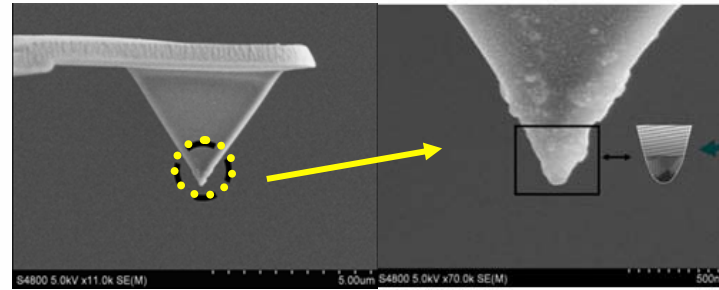
✓ Surface heterogeneity leads to adhesion force distributions

# Modeling Adhesion Forces Surface Characterization

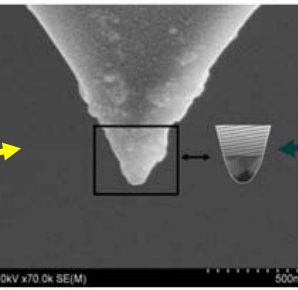
- Geometry  
- Regular



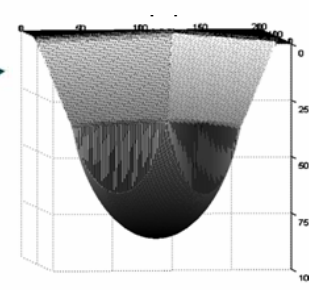
FESEM micrograph of SiO<sub>2</sub>



Si<sub>3</sub>N<sub>4</sub> Nanosize pyramidal tip

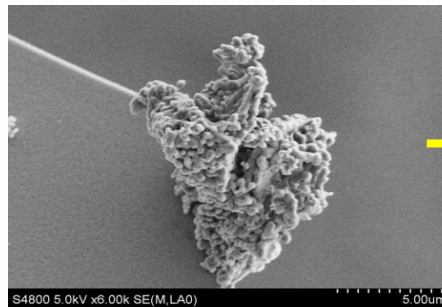


Zoomed-In view: ROC ~ 75nm

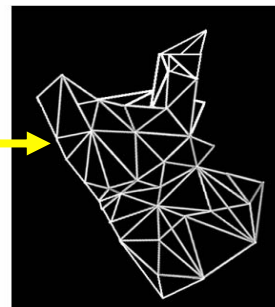


Modeled tip

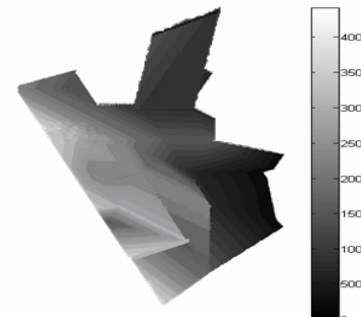
- Geometry  
- Irregular



FESEM micrograph of Al<sub>2</sub>O<sub>3</sub>



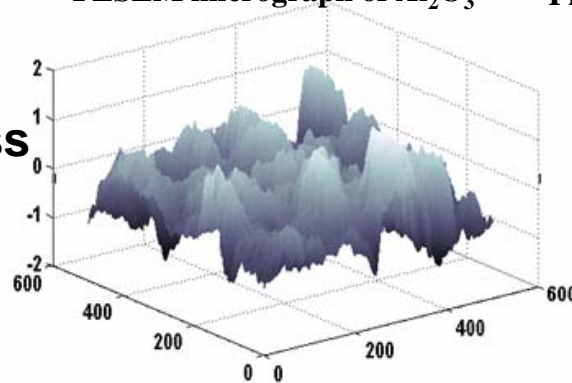
PhotoModeler wire-mesh  
(Top-view)



Top-view of the constructed surface

(Height data are in nanometers)

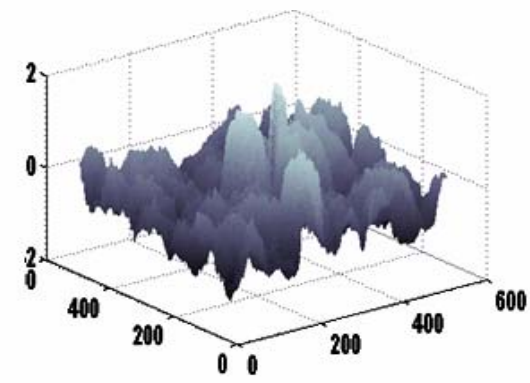
- Roughness



AFM scan of Chrome surface

FFT →

$$z_{x,y} = \sum_{k=0}^{M-1} \sum_{l=0}^{N-1} Z_{k,l} e^{i 2 \pi \left[ \varphi_{k,l} + \frac{kx}{m} + \frac{ly}{n} \right]}$$

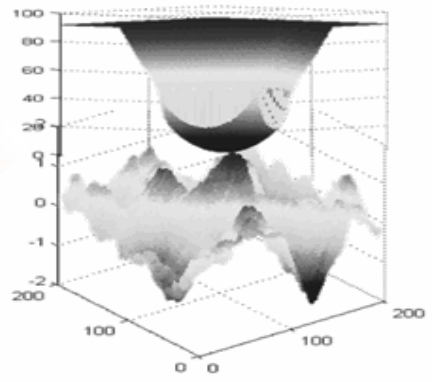
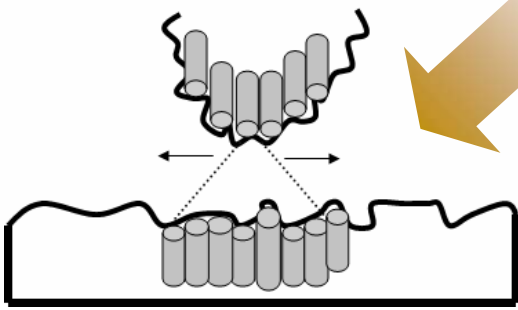


FFT generated Chrome roughness

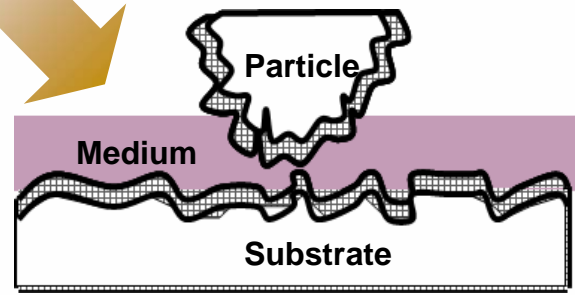
(from phase shift)

# van der Waals (vdW) and Electrostatic (ES) Force Model Description

**vdW**



**ES**



+

$$F_{1j} = C \frac{\partial}{\partial D} \iiint dV_j \iiint \frac{dV_1}{r^{16}}$$

↓

$$F = \sum_i \sum_j F_{ij}$$

Point-by-point additivity

Double Layer

$$\nabla^2 \psi = k^2 \psi \quad \text{Poisson-Boltzmann Eq.}$$

$$k = \sqrt{\frac{e^2 \sum_i z_i^2 n_{i0}}{\epsilon_0 \epsilon_r K_B T}} \quad \text{Reciprocal Debye length}$$

Constant potential boundary conditions

Columbic

$$F_{el} = \left( \frac{1}{4 \pi \epsilon} \right) \left( \frac{q^2 R (D + R)}{((D^2 + 2 R D)^2)^2} \right)$$

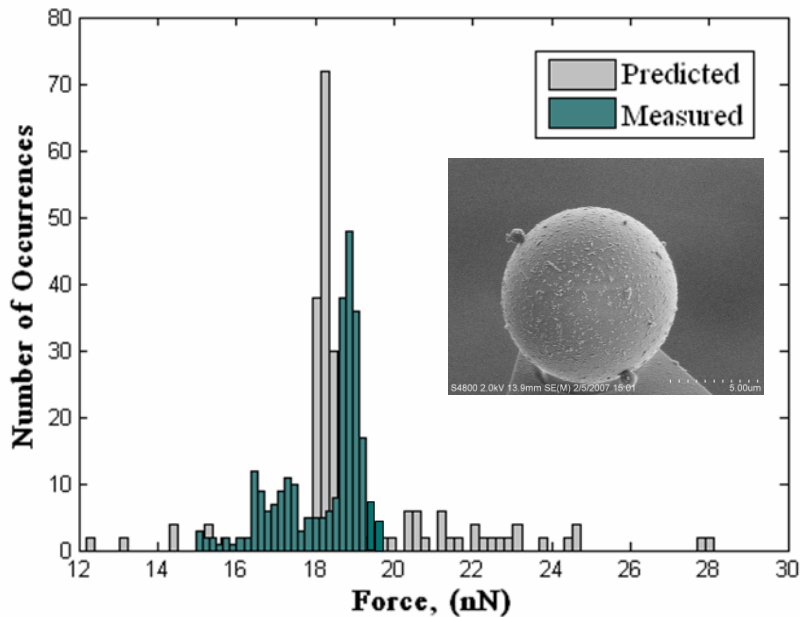
**$F_{\text{Adhesion}} = F_{\text{vdW}} + F_{\text{ES}}$**

# Adhesion in Micron-Scale Particle-Substrate System

- Particle geometry and particle and substrate roughness were measured and modeled

## Regular geometry

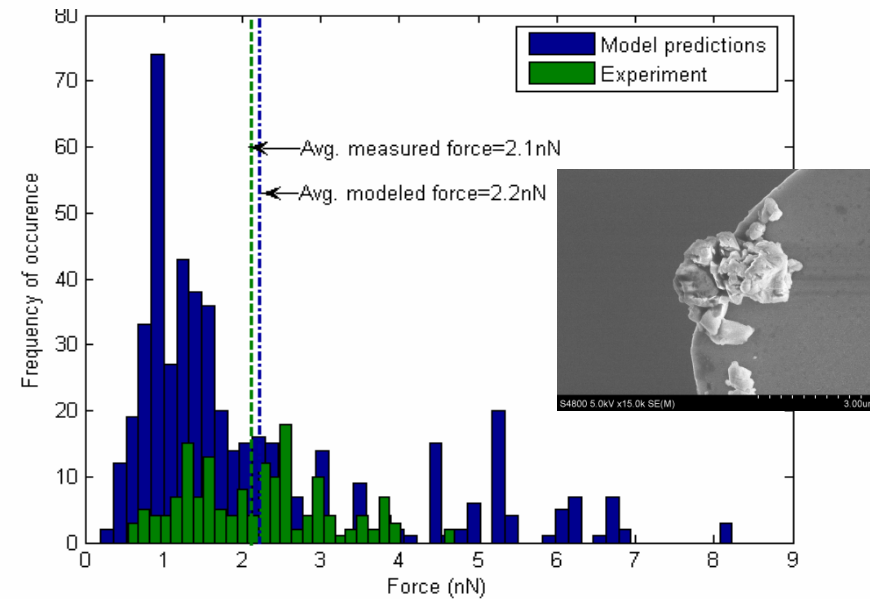
Silica particle (~3 $\mu$ ) on TaO<sub>x</sub>N<sub>y</sub> in air



$F_{,av-Measured}$ : 18 nN;  $F_{,av-Predicted}$ : 19 nN

## Irregular geometry

Silicon nitride particle 4.1  $\mu$ m on TaO<sub>x</sub>N<sub>y</sub> in DI water



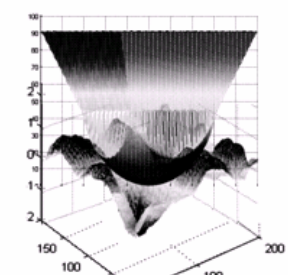
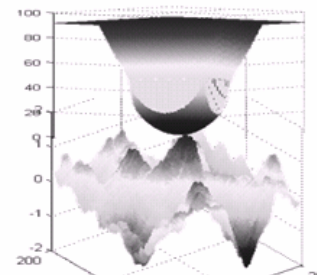
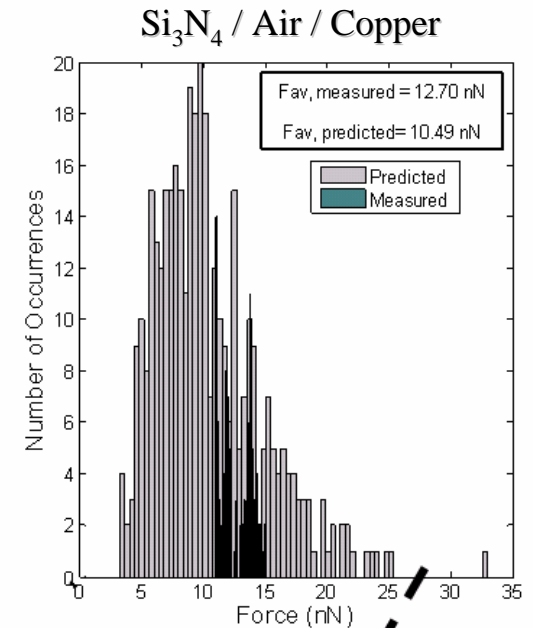
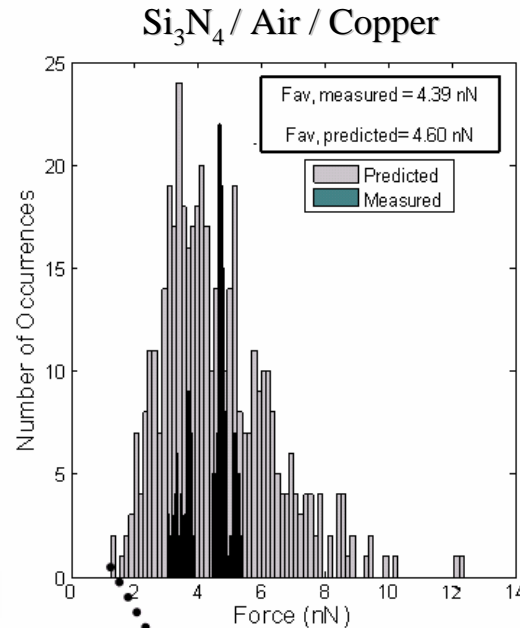
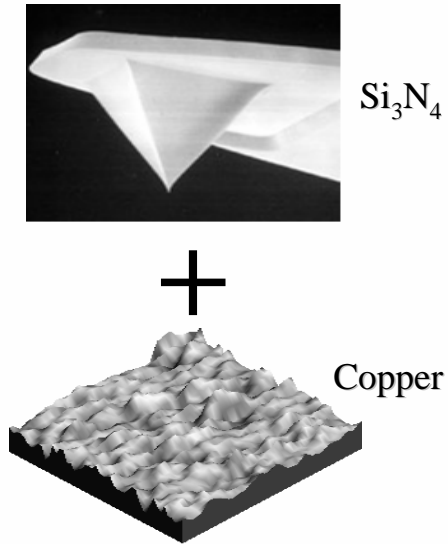
$F_{,av-Measured}$ : 2 nN;  $F_{,av-Predicted}$ : 2 nN

- Range of predicted force is wider than measured
  - ✓ Measured forces are in the range of model predictions

# Adhesion of Nanosized Body-Substrate System

- Measured and Predicted Adhesion Forces: Silicon Nitride AFM Probe on Copper Surface in Air

- Tip-1: ROC ~ 30nm
- Tip-2: ROC ~ 50nm

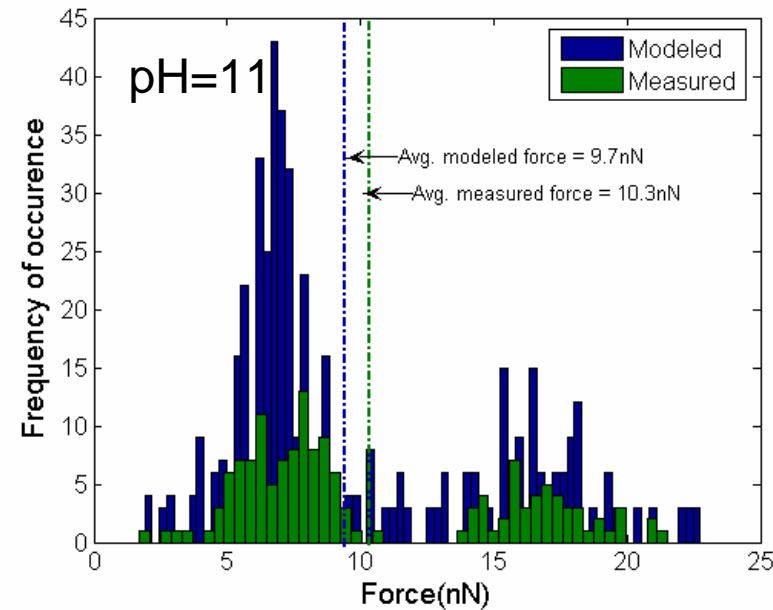
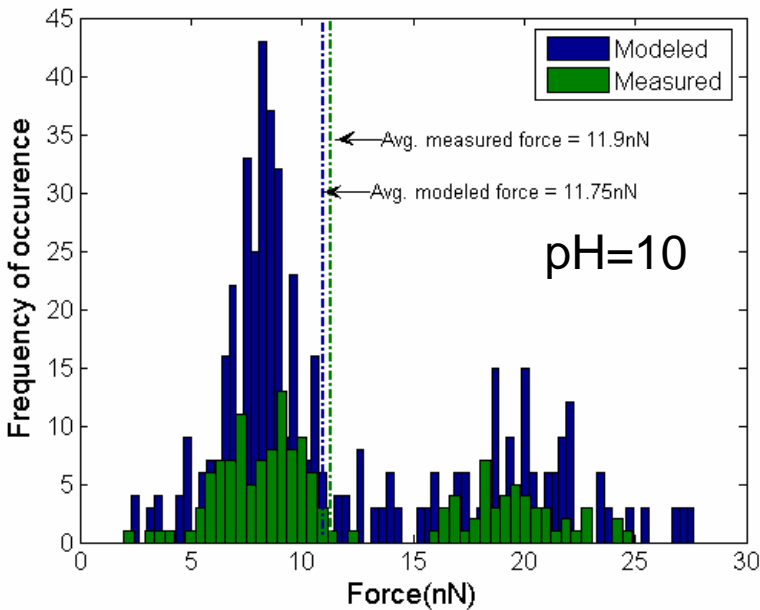
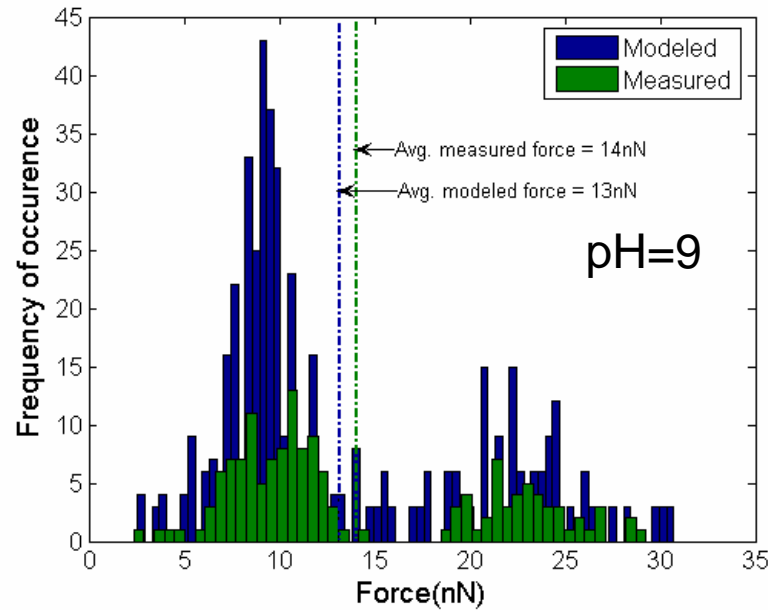


- Substrates: CrO<sub>x</sub>N<sub>y</sub>, Ru, TaO<sub>x</sub>N<sub>y</sub>, MoSi, quartz, SiO<sub>2</sub>

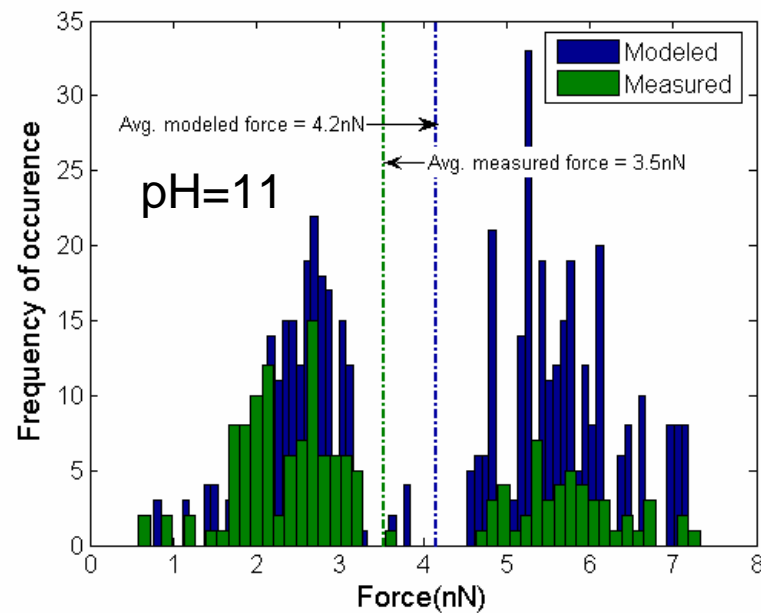
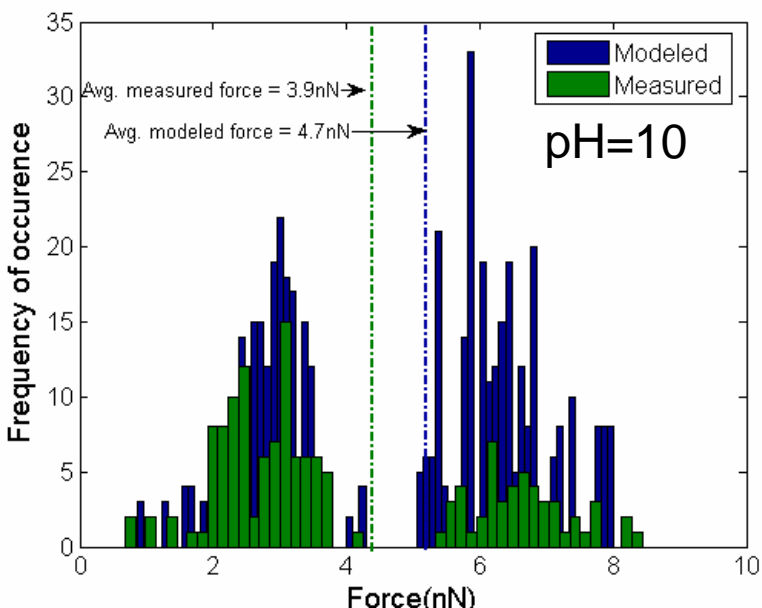
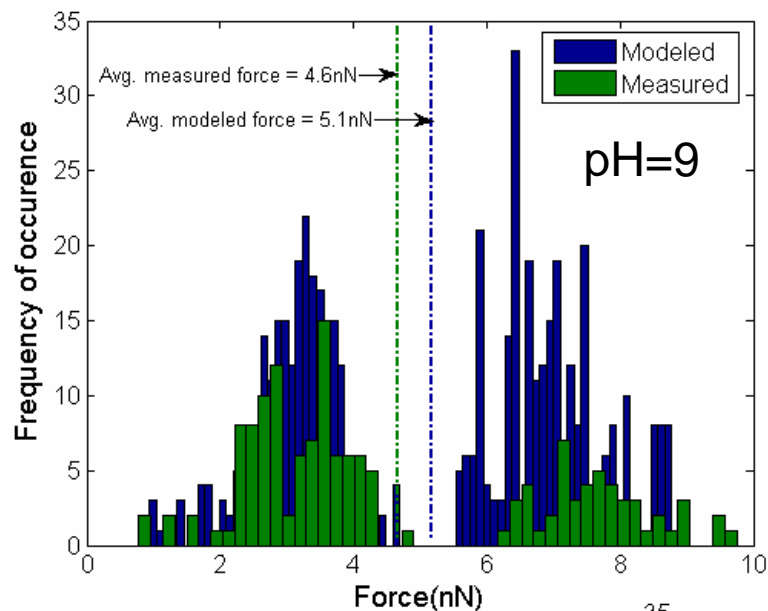
- Environments: air, DI water

✓ Measured forces are in the range of model predictions

# Interactions between $\text{Si}_3\text{N}_4$ and $\text{SiO}_2$ in Aqueous $\text{NH}_4\text{OH}$

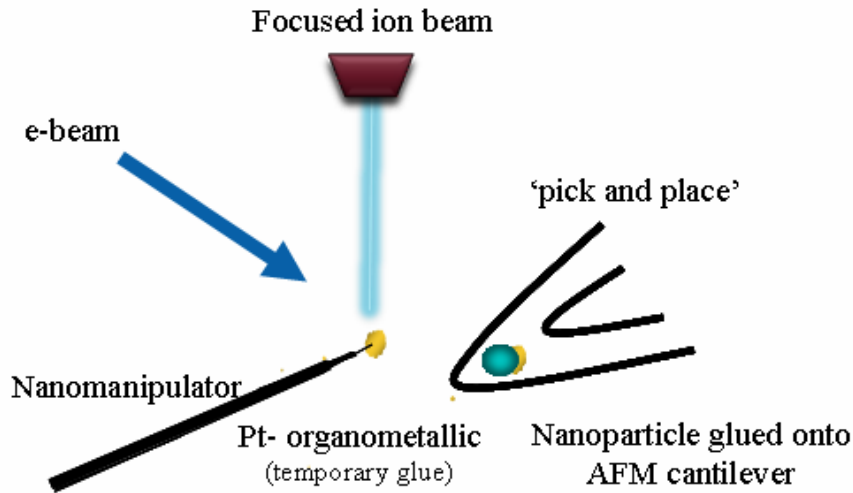


# Interactions between $\text{Si}_3\text{N}_4$ and $\text{SiO}_2$ in Aqueous $\text{NH}_4\text{OH}$

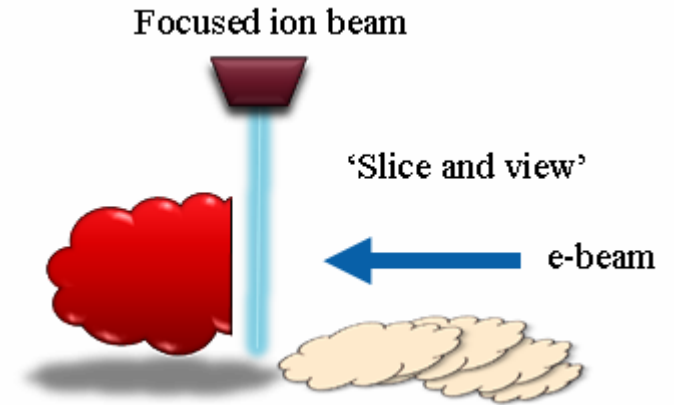


# Next Generation Experimental Approach

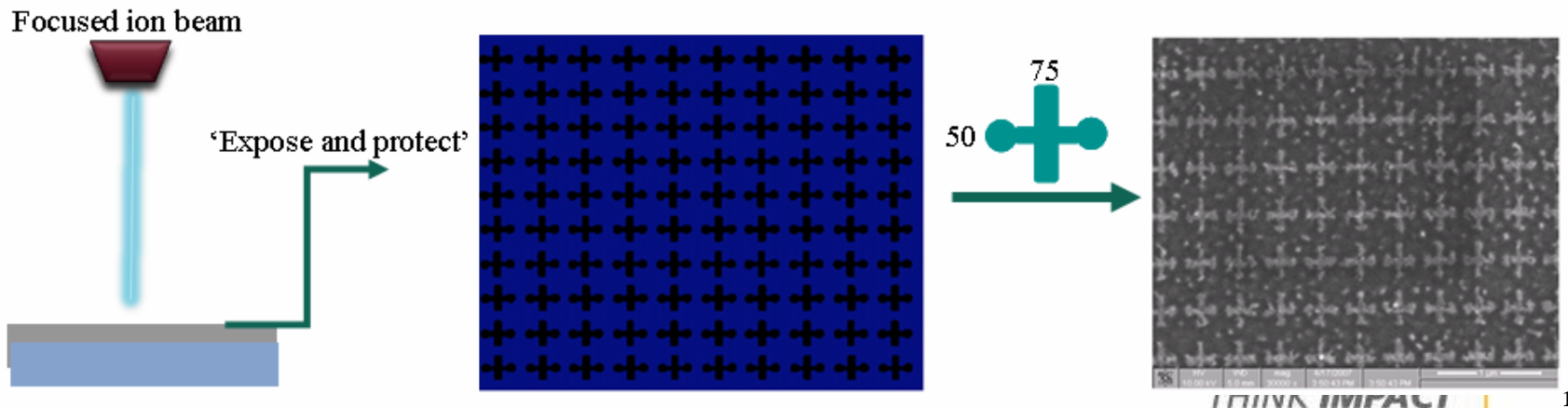
Nanoparticle mounting technique:  
“nano-welding”



Geometry characterization:  
rigorous approach



Patterned substrate preparation

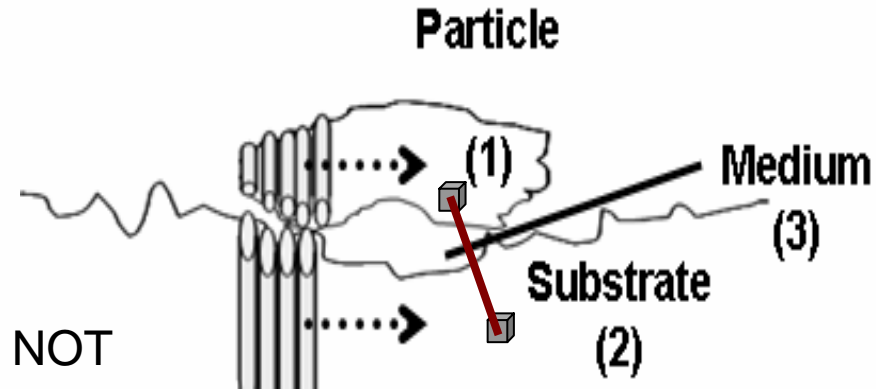


# Conventional vdW Force Modeling Approach

- Rigorous approach

$$F_{12} = -C \frac{\partial}{\partial D} \iiint dV_2 \iiint \frac{dV_1}{r^{16}}$$

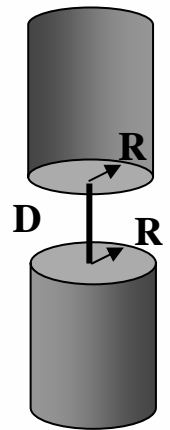
- ✓ Numerical approach
- ✓ Extremely computationally expensive- NOT practical



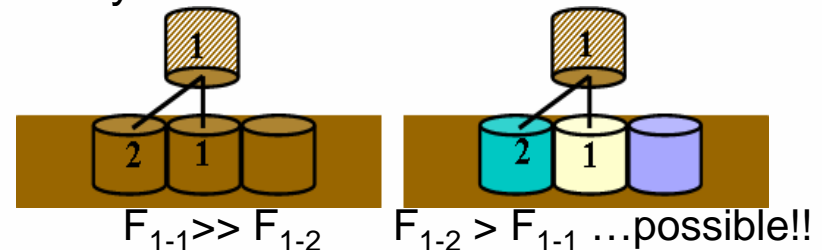
- Traditional approach (*1-1 interaction*)

$$F_{12} = \sum_{\forall i} F_{i-i} \quad \text{Hamaker's vdW expression for parallel flat plate}$$

...Where  $F_{i-i} = \frac{A(\pi R^2)}{6\pi D^3}$



- ✓ Hamaker's flat plate approximation is valid only for large cylinders ( $R \gg D$ )
  - Limited to large mesh size
- ✓ Off-axis interactions not considered
  - Limited to homogeneous surfaces

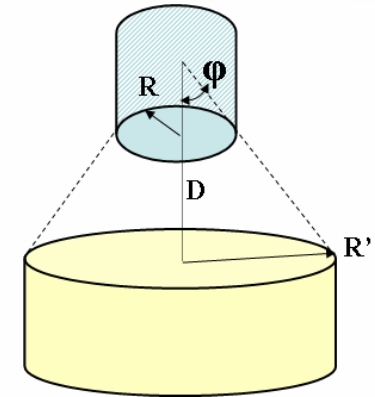
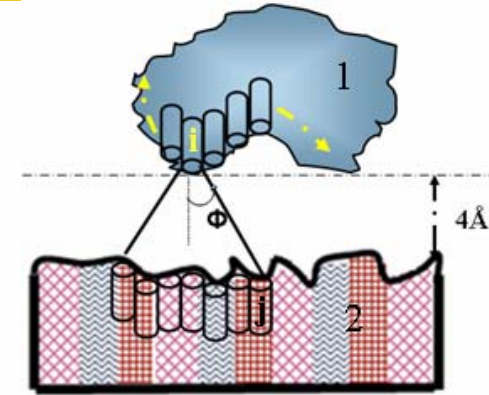
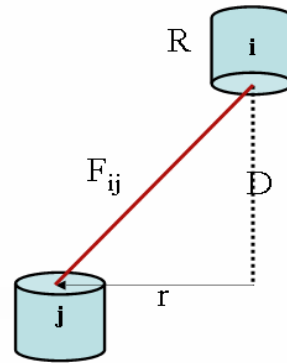
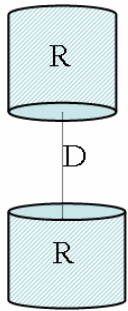


# Adhesion Force Modeling between Nanosized Inhomogeneous Surfaces

- vdW Force (*1-many interactions*)

- Mathematical surfaces are discretized into fine mesh of small cylindrical elements

$$F_{12} = - C \frac{\partial}{\partial D} \iiint dV_2 \iiint \frac{dV_1}{r^{16}} = \sum_i \sum_{\forall j} F_{ij}$$



## View angle ( $\phi$ ) of cylindrical element:

- Provide vdW-dominated region
- No analytical expression available

## vdW force co-axial cylinders

- Analytical expression available only for large cylinders

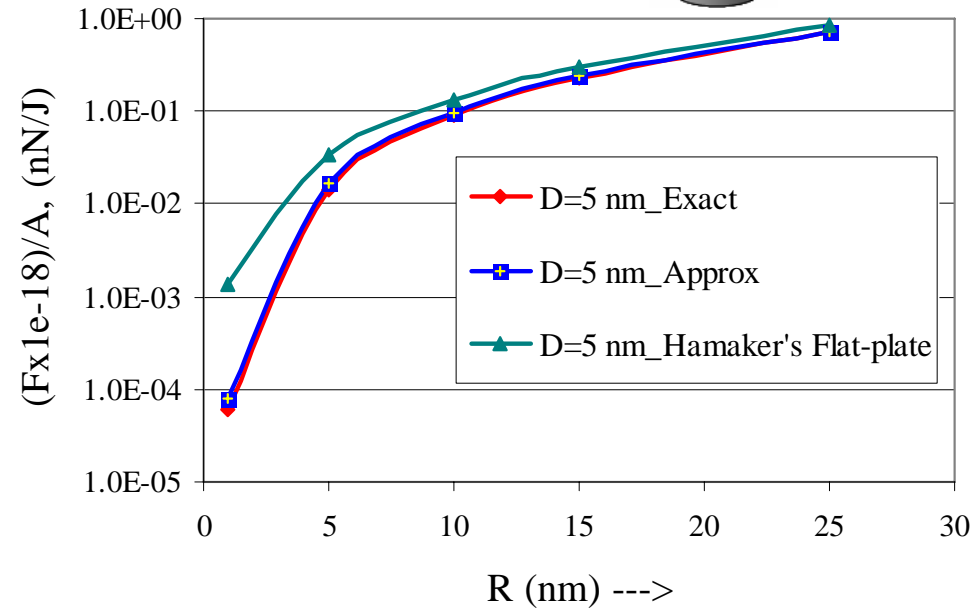
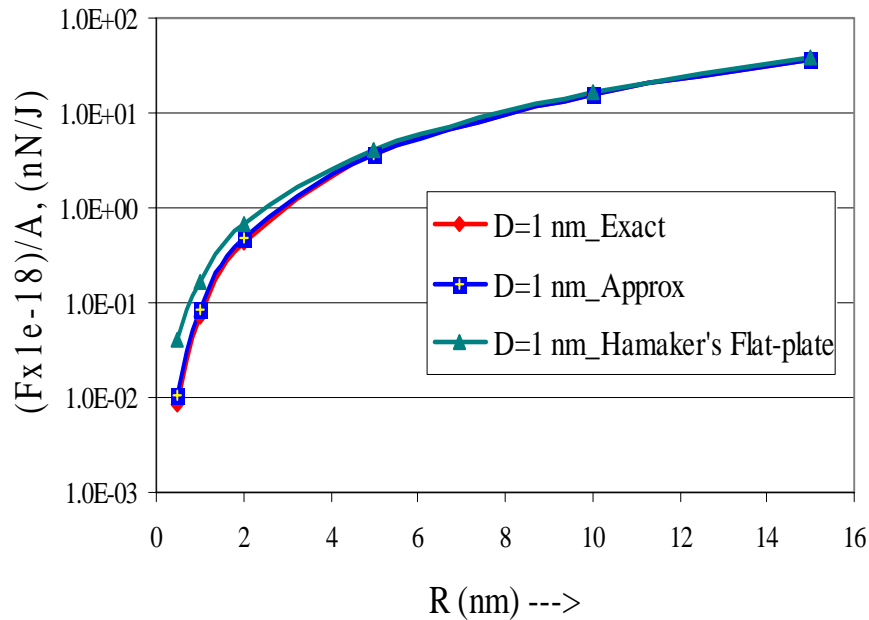
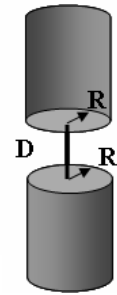
## vdW force non-axial cylinders

- No analytical expression available

✓ Analytical expressions for these interactions are required to reduce computation time

# Validation of the Derived vdW Force Expression

- A comparison of approximated and exact solution

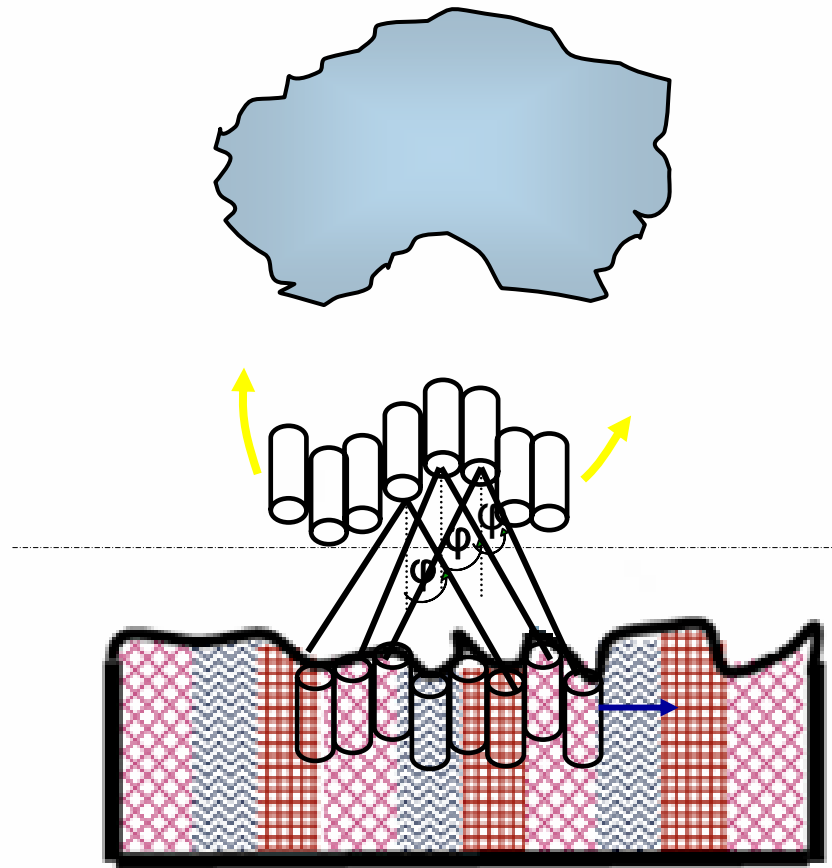


- Derived analytical expression matches well with exact solution obtained numerically
- Hamaker's flat plate approximation can not be used for fine mesh size in vdW force calculation

# Proposed Modeling Approach

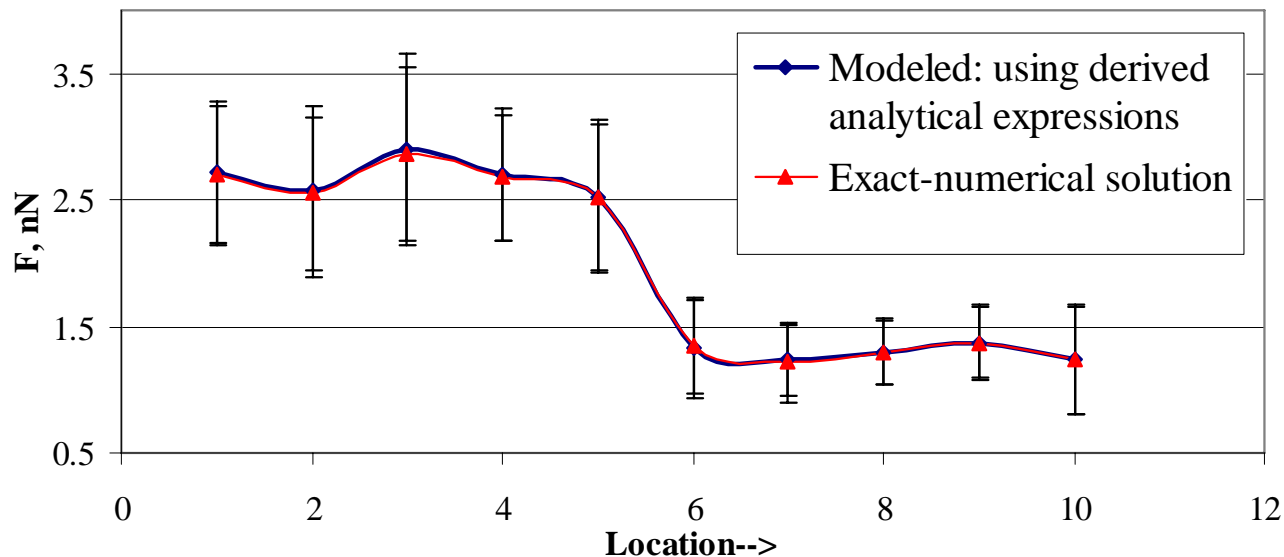
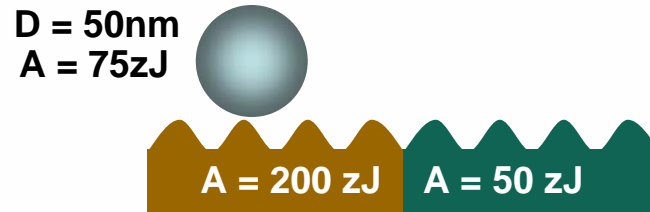
- **vdW Force**

$$F_{12} = -C \frac{\partial}{\partial D} \iiint dV_2 \iiint \frac{dV_1}{r^{16}} = \sum_i \sum_{j(\varphi)} F_{ij}$$



# Validation

- **Theoretical validation of modeling approach**
  - Smooth sphere and flat plate with defined roughness



- Derived approximate analytical expressions with proposed modeling approach give similar result as the exact numerical solution
- Force measurement between nanoparticles and patterned surface – In process

# Conclusions

- **Continuum vdW force models can be applied from micron- to nano-scale**
- **A finite volume methodology has been identified to describe nanopatterned regions**
  - Validated theoretically
  - Experimental work still underway

# Acknowledgments

- **Financial Support Provided By**
  - Purdue Shreve Trust
  - Intel
  - NSF ERC for Structured Organic Particulate Systems (C-SOPS)